

## PATENT ABSTRACTS OF JAPAN

(11)Publication number : 05-264590

(43)Date of publication of application : 12.10.1993

(51)Int.Cl.

G01R 1/073

G01B 7/28

G01R 31/26

H01L 21/66

(21)Application number : 04-090255

(71)Applicant : HITACHI ELECTRON ENG CO  
LTD

(22)Date of filing : 16.03.1992

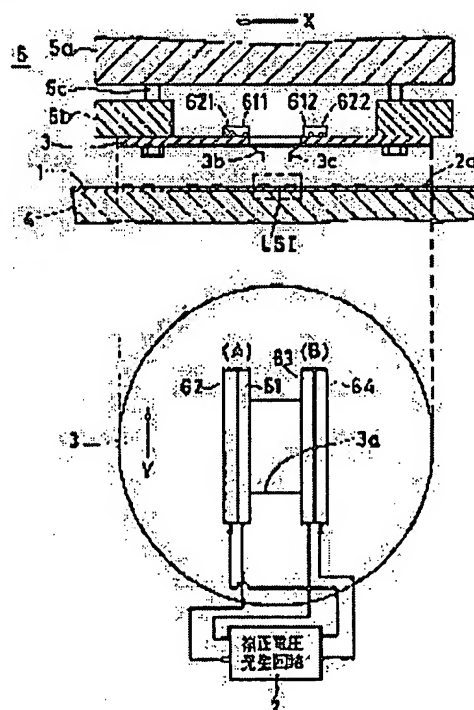
(72)Inventor : MORI HIROFUMI

## (54) WARP CORRECTION MECHANISM FOR PROBE CARD

## (57)Abstract:

PURPOSE: To obtain a mechanism for correcting a warp generated on a probe card due to the rise of inspection temperature during the inspection of an LSI tip using the probe card.

CONSTITUTION: On the probe card 3 surface, warp detection piezoelectric elements 61, 63 and warp correction piezoelectric elements 62, 64 are contacted in parallel. A correction voltage generation circuit 7 is provided to input the detection voltage detected by the warp detection piezoelectric elements and supply the bend correction piezoelectric elements with a generated correction voltage with reverse phase to the detection voltage. Thus, the warp of the probe card is corrected and the probe of the probe pin surely contacts the pad terminals corresponding to the LSI tips, and so reliable LSI tip inspection becomes possible.



## LEGAL STATUS

[Date of request for examination]

28.09.1995

[Date of sending the examiner's decision of  
rejection]

[Kind of final disposal of application other than  
the examiner's decision of rejection or  
application converted registration]

[Date of final disposal for application]

[Patent number] 2802849

[Date of registration] 17.07.1998

[Number of appeal against examiner's  
decision of rejection]

[Date of requesting appeal against examiner's  
decision of rejection]

[Date of extinction of right] 17.07.2002

Copyright (C); 1998,2003 Japan Patent Office